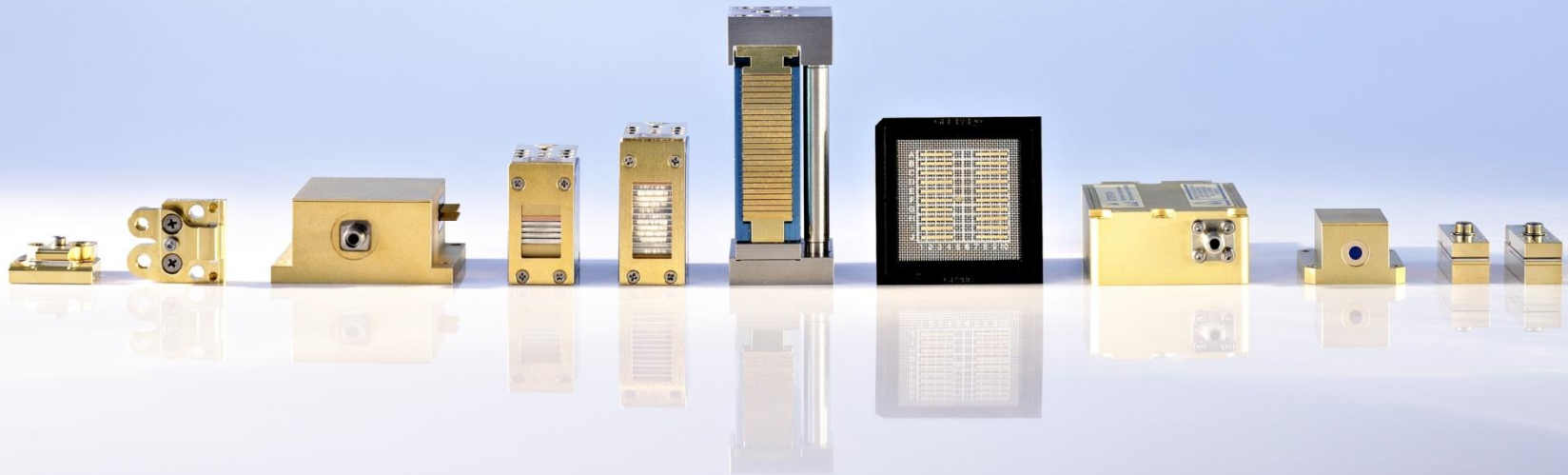


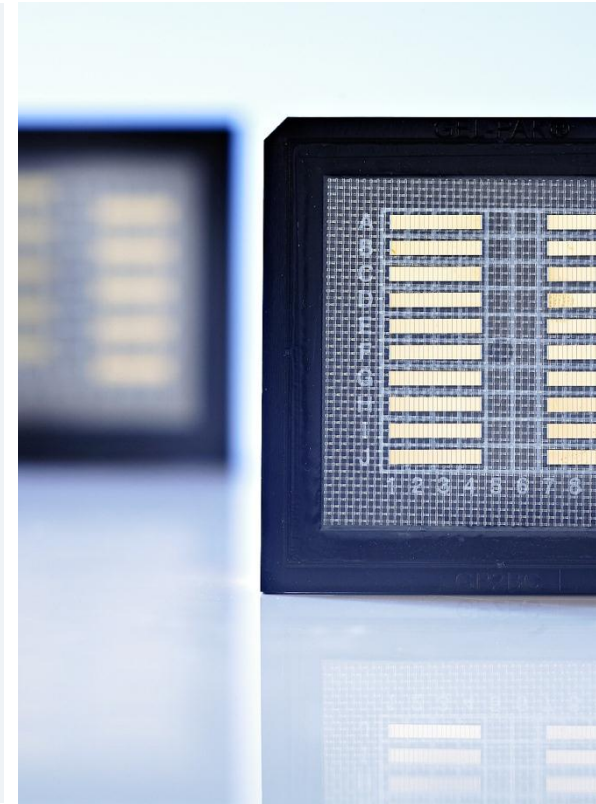


Increasing the power density towards IFE requirements: high-power laser diode bars



Speaker Martin Wölz

- **JENOPTIK and JENOPTIK Diode Lab GmbH**
- Semiconductor laser design
- Solution for 940 nm
- Solution for 880 nm
- Outlook: laser diode stacks



Corporate Center

Lasers & Material Processing



- Lasers
- Laser Processing Systems

Optical Systems



- Optics
- Micro Optics
- Optoelectronic Systems

Industrial Metrology



- Roughness and contour measurement
- Form measurement
- Dimensional measurement

Traffic Solutions



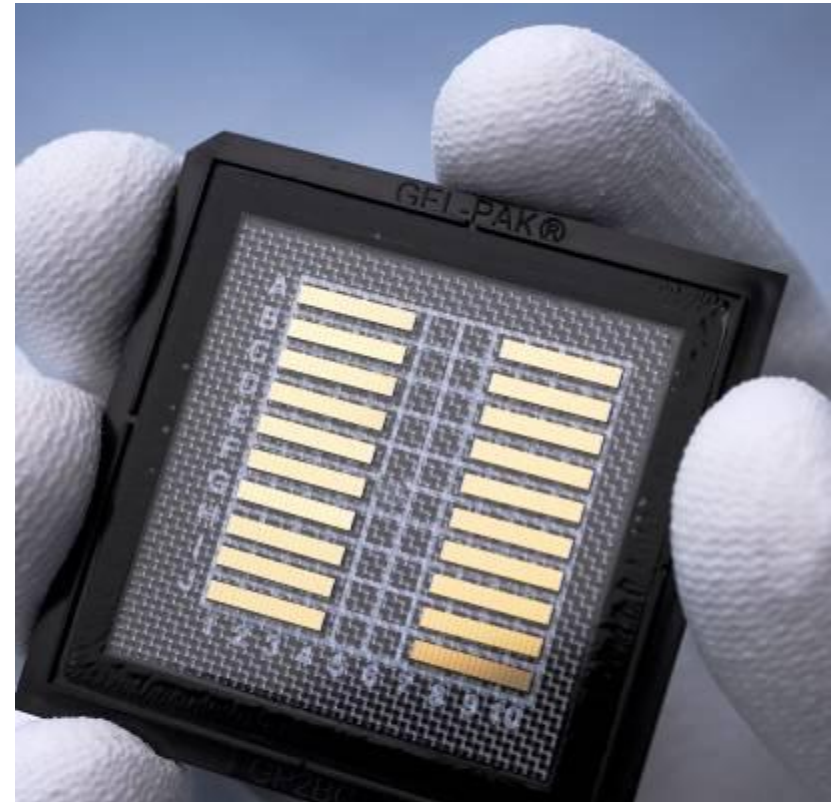
- Equipment
- Service Providing

Defense & Civil Systems



- Mechatronics
- Sensor Systems

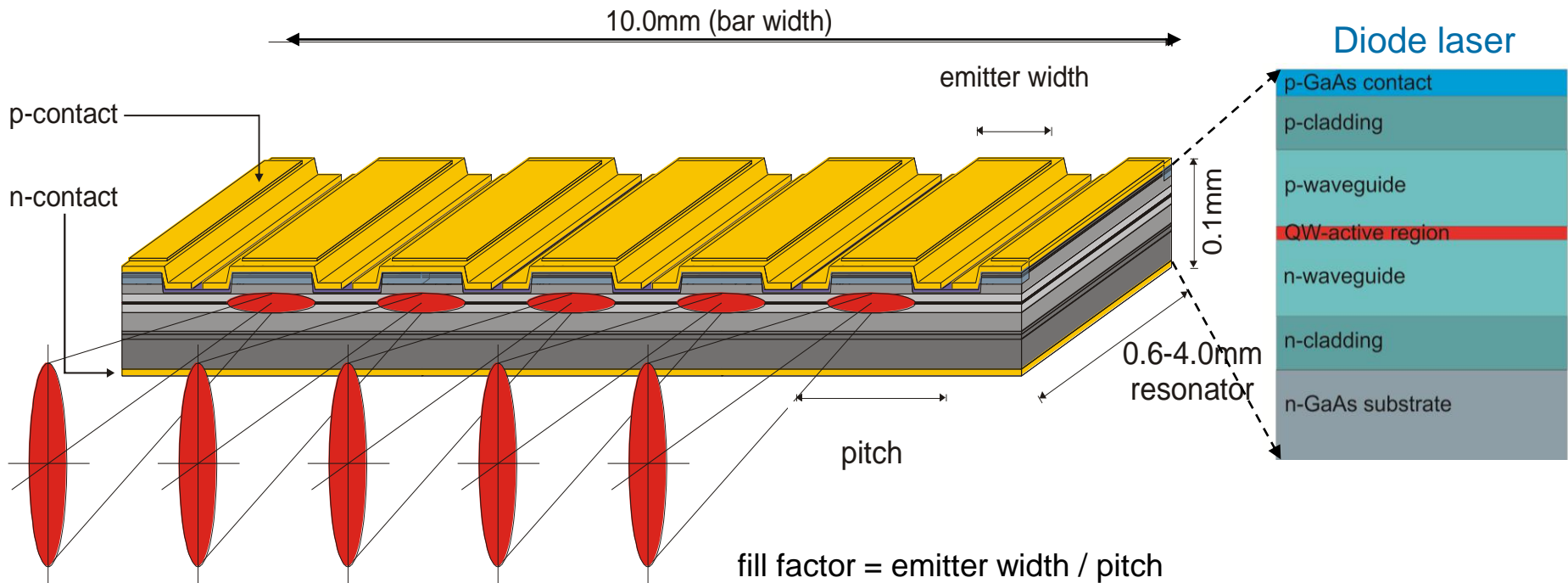
- Laser epitaxial structure design
- InGaAlAsP / GaAs-Epitaxy (MOVPE)
- GaAs-process line
- Facet-Coating process
- Single Emitter (SE) and Laser Bar
- Wavelength: 760 nm – 1060 nm
- Power range
 - Single emitter CW: 12 W
 - Bar CW: 200 W
 - Bar QCW: 500 W
- Bare bar sale



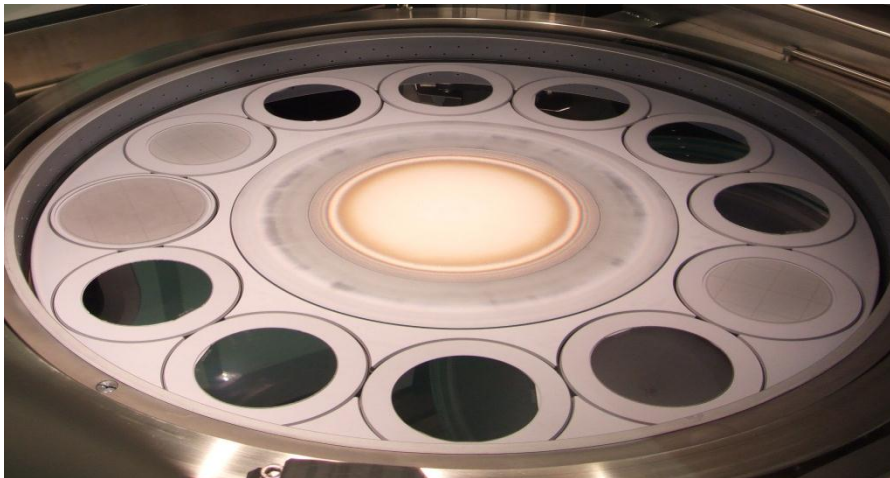
laser diode bars

Introduction

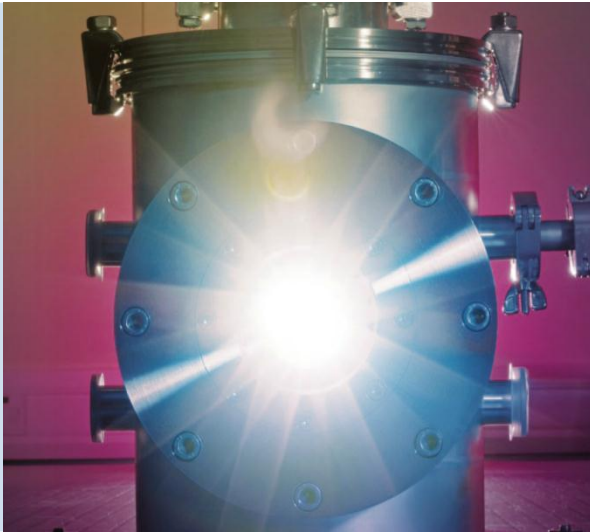
Semiconductor laser diode bar



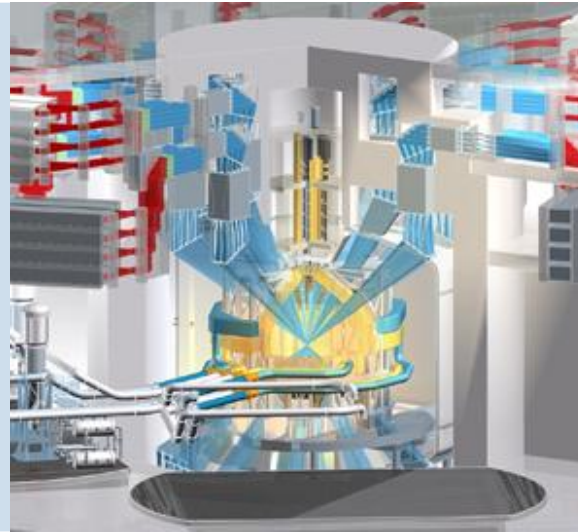
- Two multiwafer planetary reactors
 - 12 x 3" or 4"
 - 8 x 3" or 4"
- Layer characterisation: HRXRD, C-V profiling, EL, PL, SEM, (SIMS)
- Foundry services
- Certified to ISO 9001:2008



What can we do for high energy class lasers?



Mason et al., 7th HEC-DPSSL Workshop (2012)



Bayramian et al., Fusion Sci. Technol. 60, 28 (2011)

- 10 J, 10 Hz **DiPOLE** prototype
 - Yb:YAG, 940 nm, 1ms QCW
 - 40kW pulse power from 192 bars
- 100 J ...

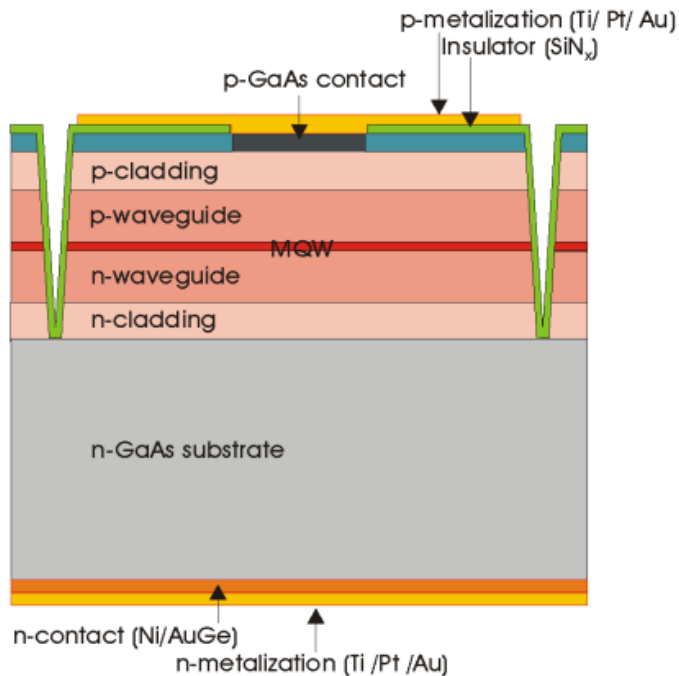
- **LIFE**: projected 2.2 MJ, 16 Hz
 - Nd:glass, 880 nm, 200 μ s QCW
 - 50 GW pulse power from ? bars



increase the power density !

Introduction

Broad area laser diode elements

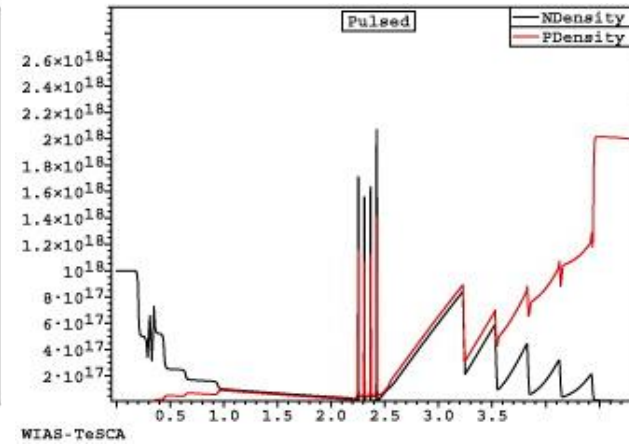
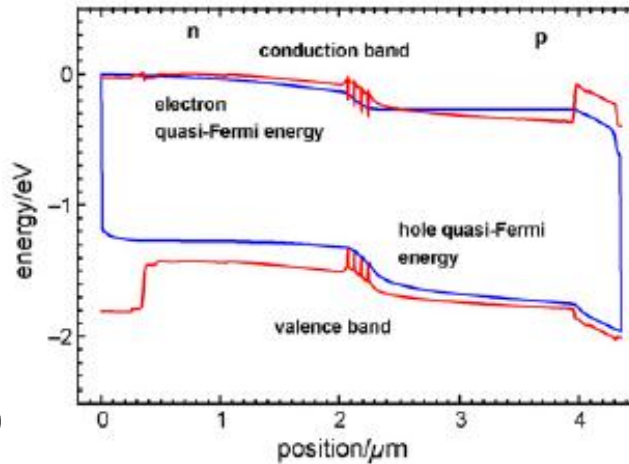
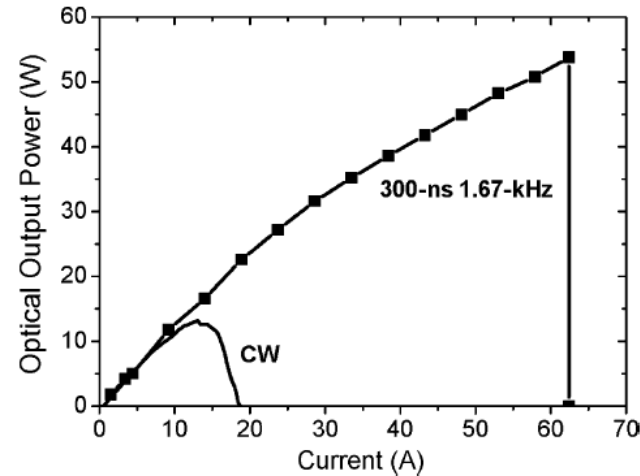


Pietrzak, Dissertation (2011)

device layout	design parameters	laser performance
vertical	epitaxial layers <ul style="list-style-type: none"> • thickness • composition (E_g, n) 	<ul style="list-style-type: none"> • wavelength • carrier confinement • vertical mode confinement • gain, absorption • “fast axis” divergence
lateral	<ul style="list-style-type: none"> • metal contact • separation of emitters 	<ul style="list-style-type: none"> • current density • lateral mode confinement • “slow axis” divergence
mirrors	<ul style="list-style-type: none"> • material, thickness • reflectivity 	<ul style="list-style-type: none"> • laser threshold • slope efficiency • reliability

Vertical structure design

Carrier confinement



Pietrzak et al., *Semicond. Sci. Technol.* 24, 035020 (2009)
 current-induced heating
+ carrier leakage

Wenzel et al., *New J. Phys.* 12, 085007 (2010)
 band bending
 carrier accumulation

→ degraded slope efficiency

→ reduced effective barrier
 → carrier escape

in waveguides
 + claddings

Loss mechanism: bias-induced carrier leakage

Solution: designs with higher barriers against carrier escape

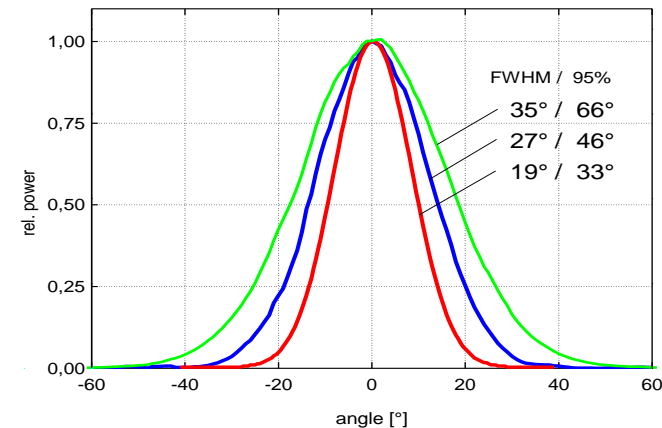
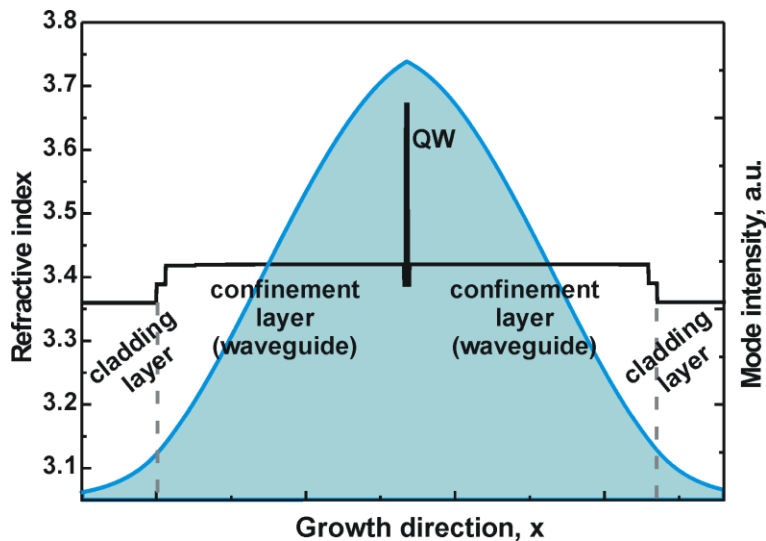
(must be balanced against series resistance)

Vertical structure design

Light confinement in large optical cavities



waveguide	thin	thick
overlap of light and charge carriers (confinement)	high Γ	low Γ
efficiency	high η	low η
fast axis divergence	large θ_{\perp}	small θ_{\perp}



material data			
θ_{\perp} (FWHM)	35°	27°	19°
Γg_0 (cm ⁻¹)	15.3	13.0	11.0
η	67%	60%	58%

Pietrzak, Dissertation (2011)

Hülsewede et al., Proc. of SPIE, 68760F (2008)

Laser dimensions for QCW application

Resonator length and fill factor



- heat dissipation in active area limits external quantum efficiency

- phenomenological model (char. Temp.)

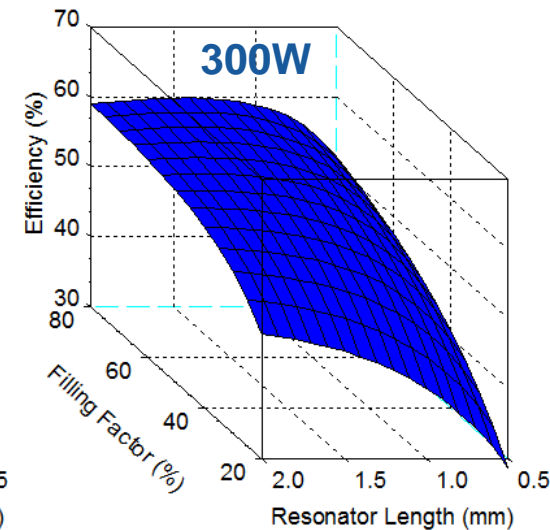
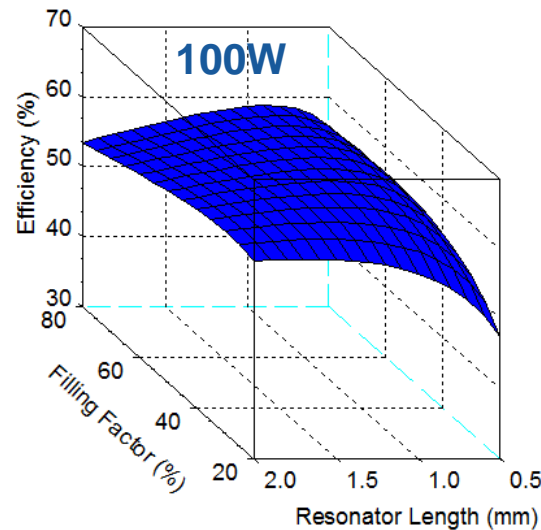
$$I_{thres} \propto e^{\Delta T/T_0}$$
$$\eta_{diff} \propto e^{\Delta T/T_1}$$

- resonator length** (e.g. 808 nm):
structure-dependent optimum for high conversion efficiency

Deichsel et al., Proc. of SPIE, 68760K (2008)

- fill factor: maximize to 75%**
 - high efficiency
 - low facet load

Erbert et al., Top. Appl. Phys. 78, Springer (2000)

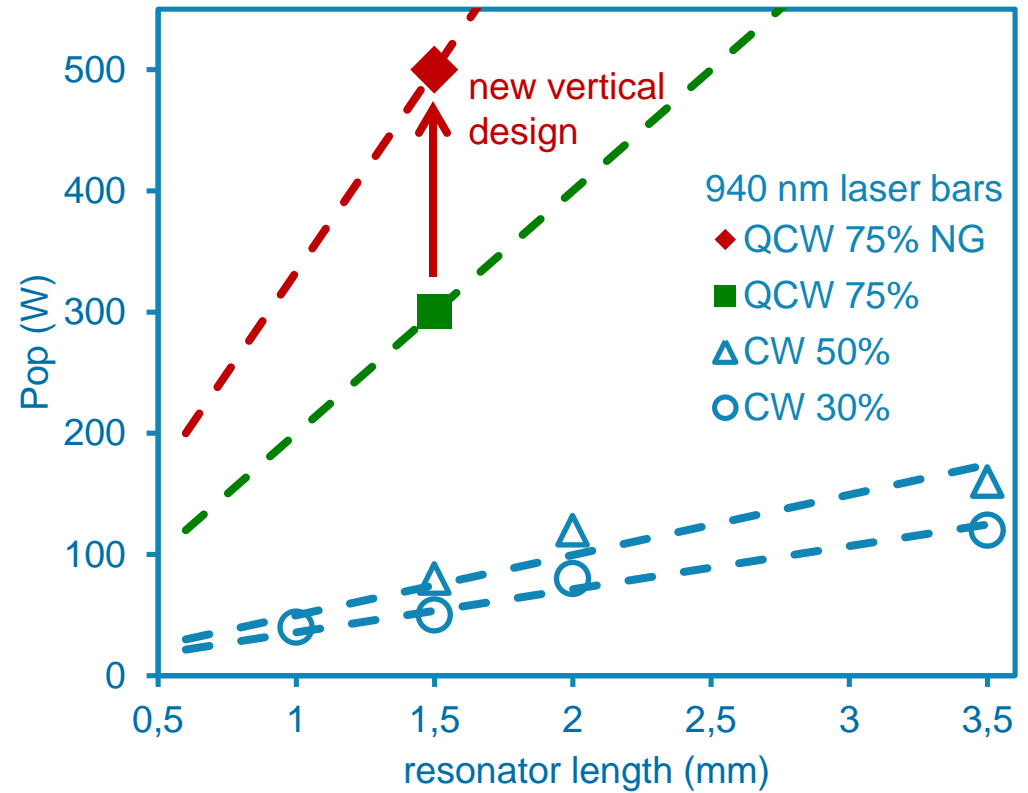


JDL New generation QCW bars

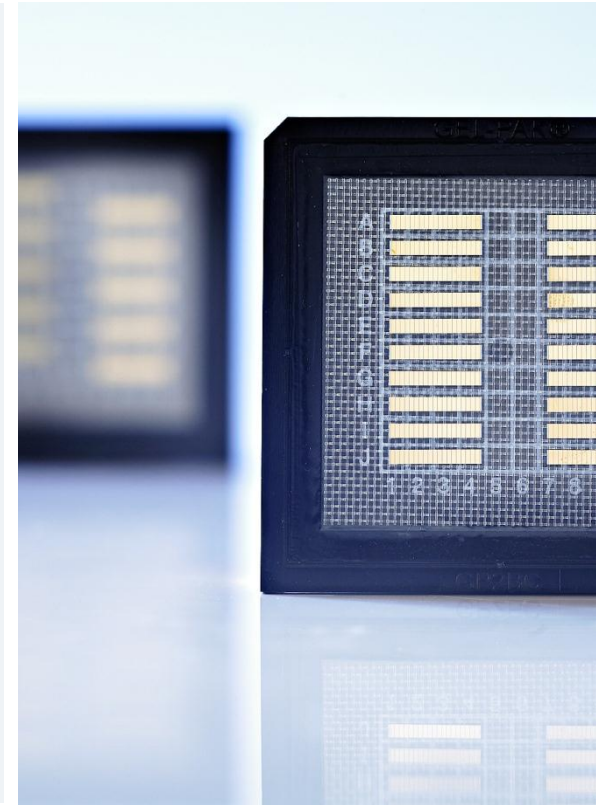
Reducing semiconductor “cost per Watt”



- new chip generation (NG) vertical design
- increased P_{op} per chip area
- decreased “cost per Watt”



- JENOPTIK and JENOPTIK Diode Lab GmbH
- Semiconductor laser design
- **Solution for 940 nm**
- Solution for 880 nm
- Outlook: laser diode stacks



New generation quasi-CW 940 nm Bars Design

(II)



Epitaxy

- strong carrier confinement
 → reduced slope efficiency degradation
 → P_{\max} from 300W to 500W
- low optical loss α_i
 → longer resonator possible

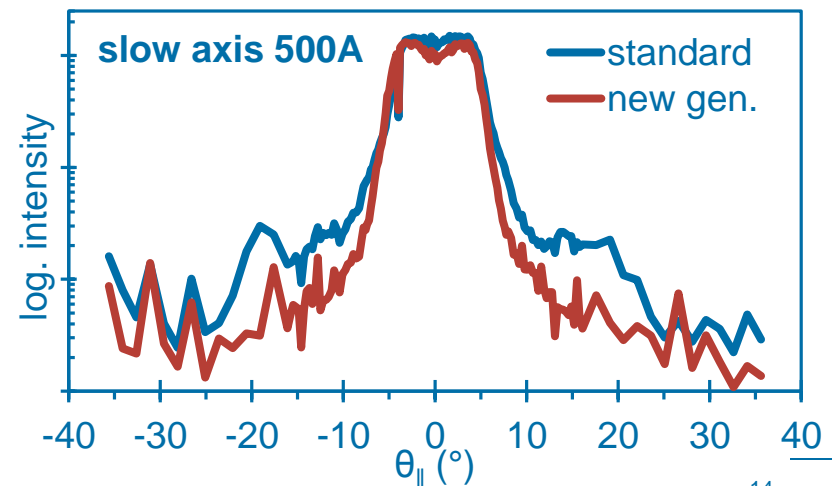
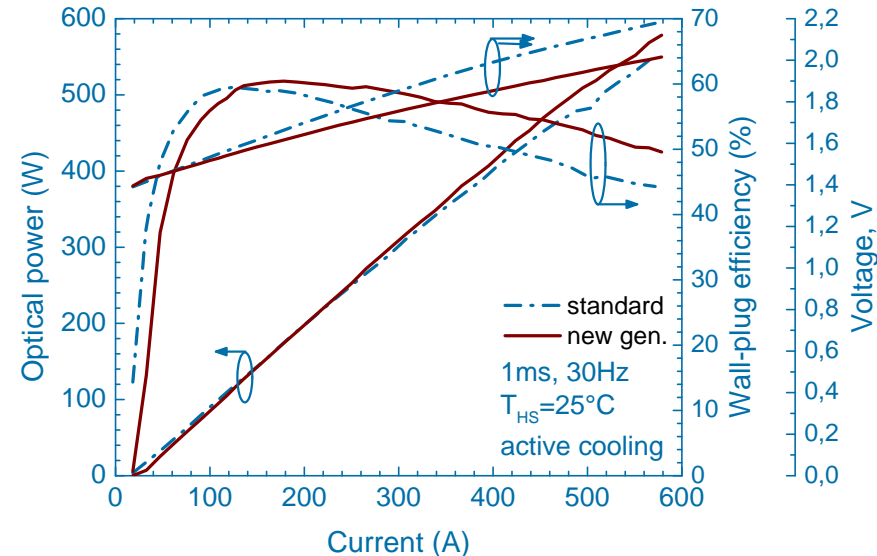
	standard	new gen.
α_i (cm ⁻¹)	0,77	0,36

Pietrzak et al., Proc. of SPIE 896528 (2014)

- thicker waveguide
 → narrow fast axis divergence

Layout (75% fill factor)

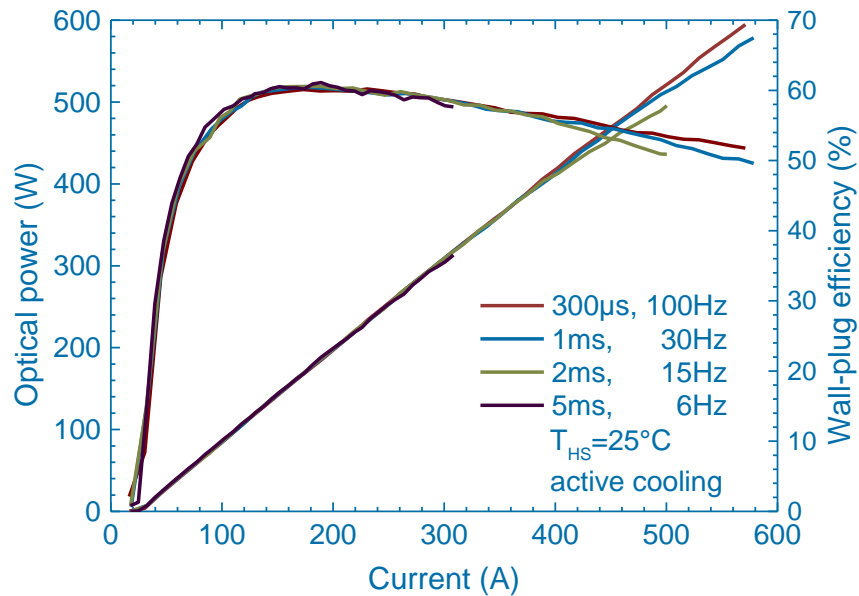
- 37 x 190 μ m emitters
- better lateral mode confinement
 → narrow slow axis divergence



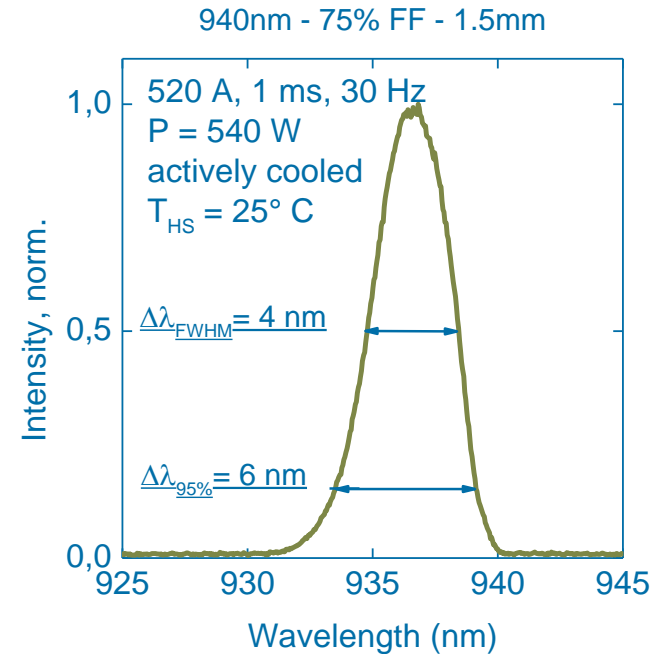
New generation quasi-CW 940 nm Bars

Design limits

(III)



- no thermal roll-over up to 500W at 1ms, 30Hz
- longer pulse accessible with longer resonator

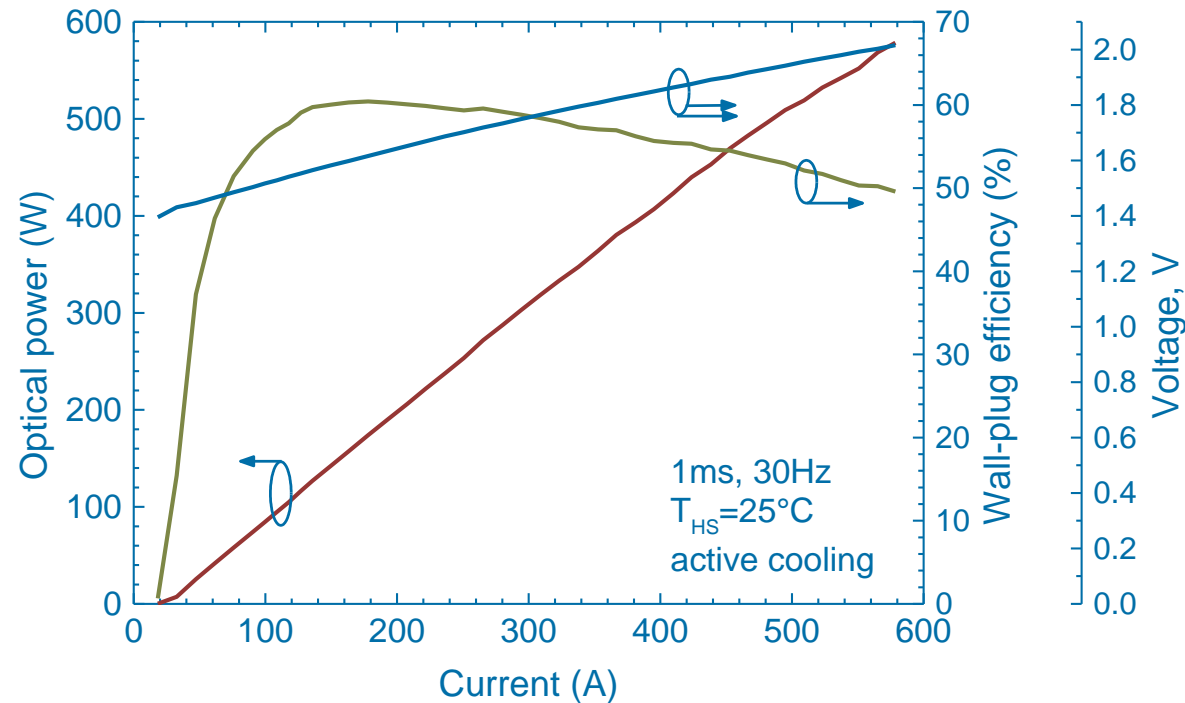


- $\Delta\lambda_{FWHM} = 4 \text{ nm}$ at P_{max}

New generation quasi-CW 940 nm Bars

Power-voltage-current characteristic

(IV)



Measurement conditions:
1ms, 30Hz, $T=25^{\circ}\text{C}$

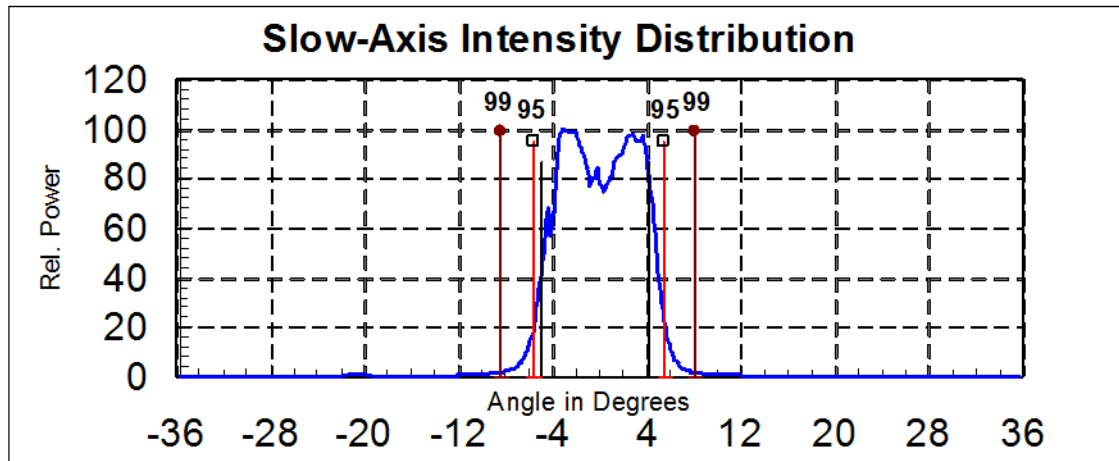
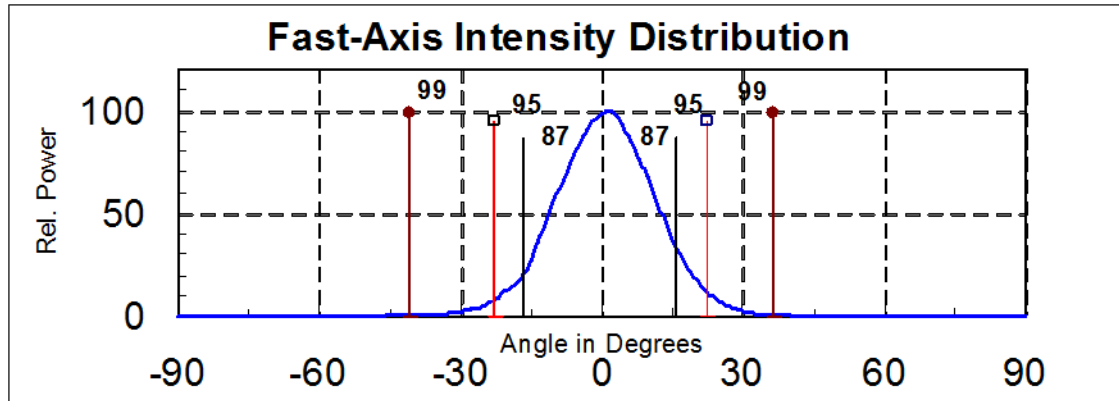
- $P_{op} = 500 \text{ W}$
- $I_{op} = 485 \text{ A}$
- $S_{op} = 1.17 \rightarrow 0.85 \text{ W/A}$
- $\eta_{max} = 60\%$
- $\eta_{op} = 53\%$

- 75% FF, $L=1.5 \text{ mm}$ (37 Emitters, $W = 190 \mu\text{m}$)
- In progress: lifetime test at $P_{op} = 400\text{W}$ operation
- Next: qualification and release for 500W operation, JDL-BAB-75-37-940-TE-500-1.5

New generation quasi-CW 940 nm Bars

Far-field profiles

(V)



Measured at:
 $I = 500A$ (1ms, 18ms, $T = 25^{\circ}C$)

Fast axis:

- $\theta_{FWHM} = 22.5^{\circ}$
- $\theta_{95\%} = 45.5^{\circ}$

Slow axis:

- $\theta_{FWHM} = 9.2^{\circ}$
- $\theta_{95\%} = 11.1^{\circ}$

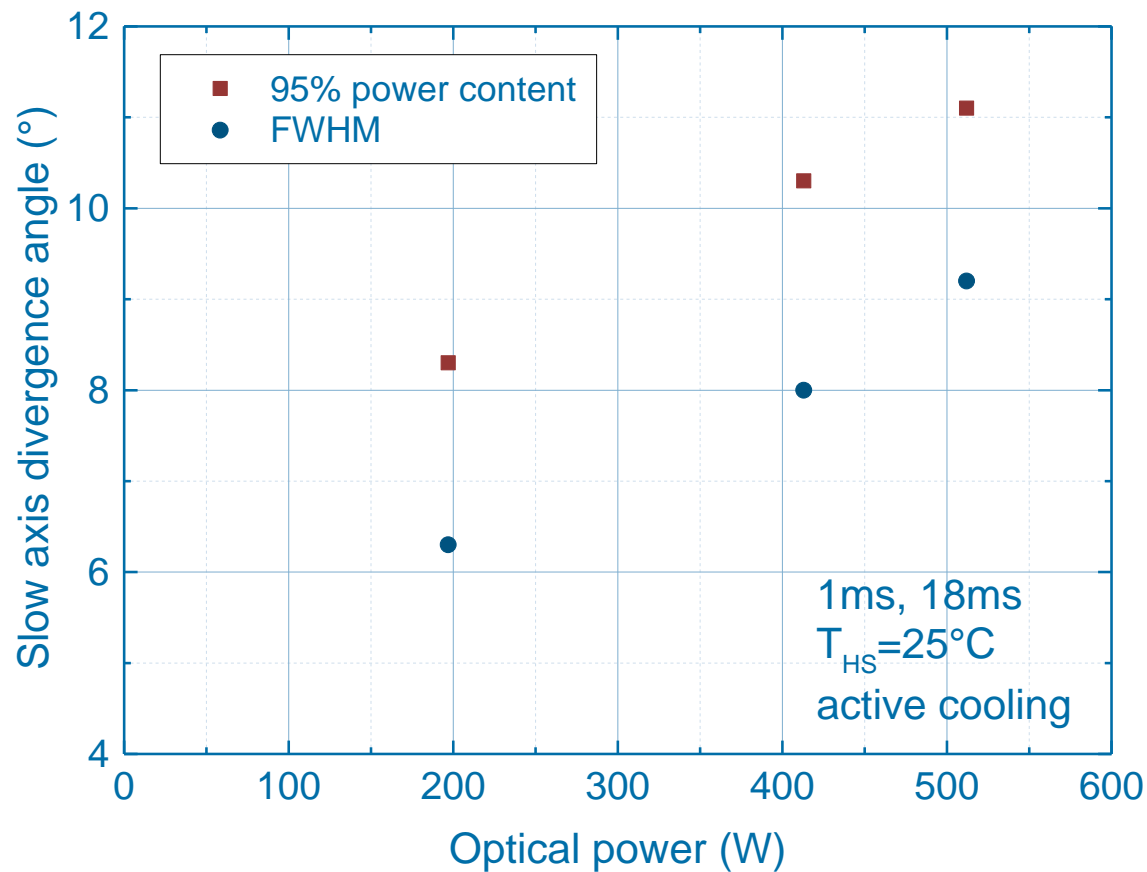
New generation quasi-CW 940 nm Bars

Slow axis

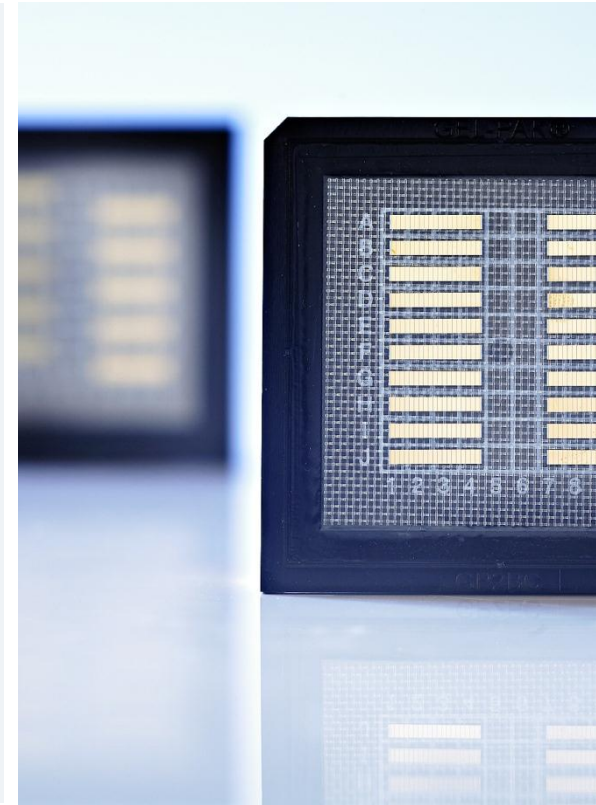
(VI)



Measurement conditions: 1ms, 18ms, T=25°C



- JENOPTIK and JENOPTIK Diode Lab GmbH
- Semiconductor laser design
- Solution for 940 nm
- **Solution for 880 nm**
- Outlook: laser diode stacks



New generation quasi-CW 880 nm Bars Design

(I)



Epitaxy:

Pietrzak et al., Proc. of SPIE 896528 (2014)

- 1) better carrier confinement
→ high internal efficiency η_i
→ higher P_{op}
- 2) thick waveguide
→ narrow fast axis divergence
- 3) high α_i negligible for short resonator

Layout as for 940 nm:

75% 37E 190 μ m 1.5mm
→ narrow slow axis divergence

	reference	new gen.
J_{th} (mA/cm ²) * ↗	166	253
η_d (%) *	87	86
η_i (%) high	97,5	97,7
Γ_{g0} (cm ⁻¹) ↗	12,7	21,4
α_i (cm ⁻¹) high	0,91	1,04
J_0 (mA/cm ²)	88	169,1

* 1.6 mm resonator
Mobarhan, Newport App. Note (1999)

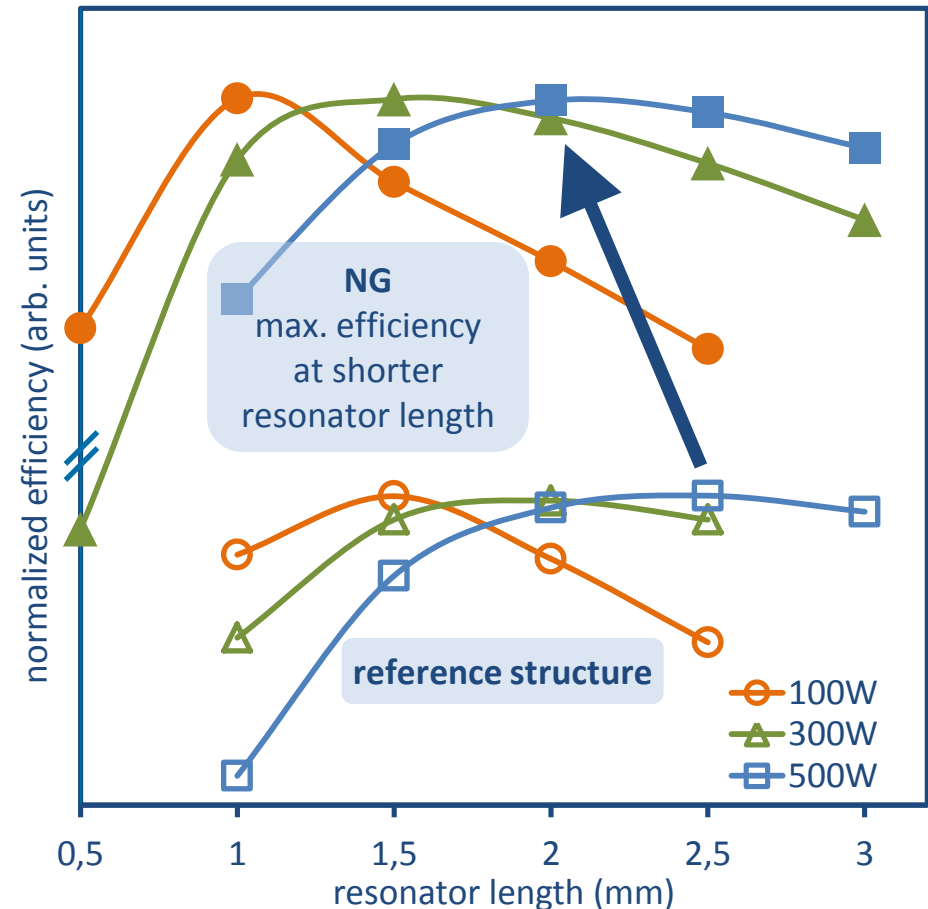
New generation quasi-CW 880 nm Bars

Better efficiency → reduced “cost / Watt”

(II)



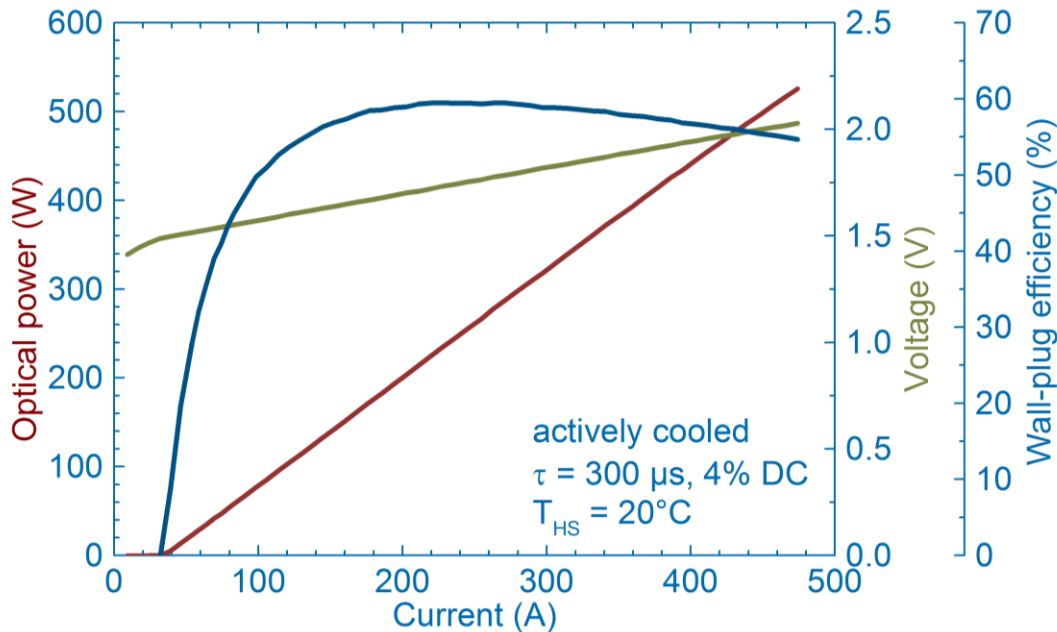
- recall phenomenological model based on char. Temp.
 $I_{thres} \propto e^{\Delta T/T_0}$
 $\eta_{diff} \propto e^{\Delta T/T_1}$
- input parameters T_0, T_1
- new generation (NG) structure has efficiency maximum for smaller chip



New generation quasi-CW 880 nm Bars

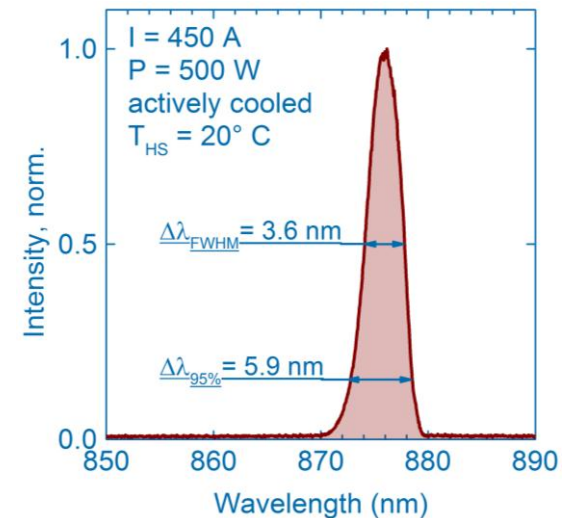
Power-voltage-current characteristic

(III)



- $P_{\text{op}} = 500 \text{ W}$
- $I_{\text{op}} = 450 \text{ A}$
- $S_{\text{op}} = 1.21 \rightarrow 1.17 \text{ W/A}$
- $WPE_{\text{max}} = 59.5\%$
- $WPE_{\text{op}} = 55\%$

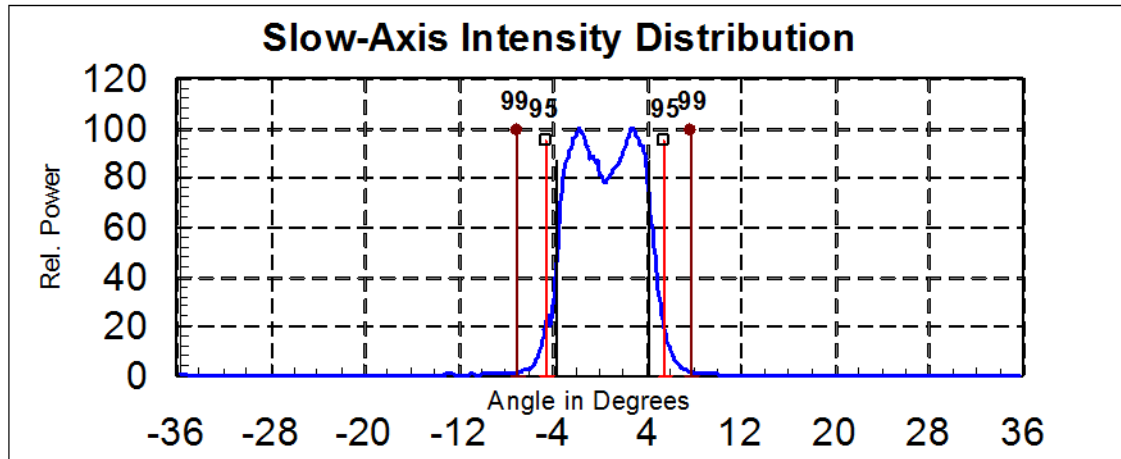
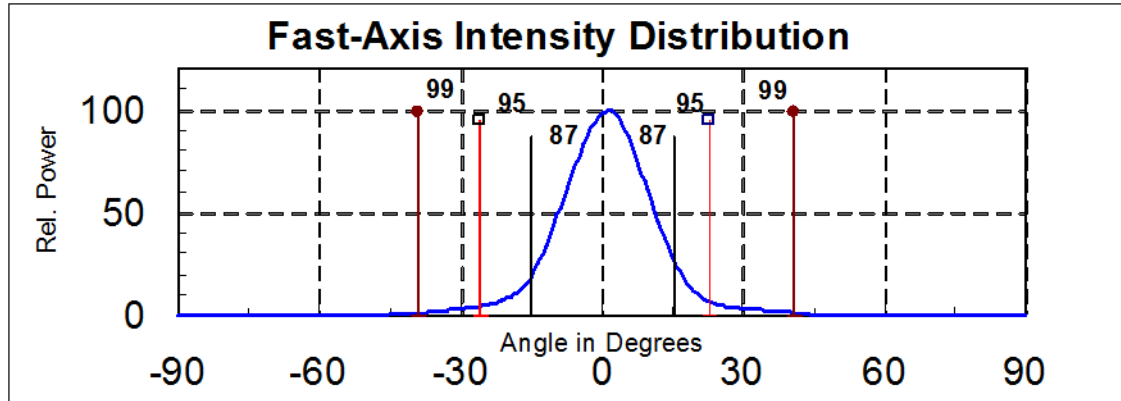
- 75% FF, $L=1.5 \text{ mm}$ (37 Emitters, $W = 190 \mu\text{m}$)
- In progress: lifetime test at $P_{\text{op}} = 400\text{W}$ operation
- Next: qualification and release for 500W operation,
JDL-BAB-75-37-880-TE-500-1.5



New generation quasi-CW 880 nm Bars

Far-field profiles

(IV)



Measured at:
I = 400A (300 μ s, 10ms, T=25°C)

Fast axis:

- $\theta_{FWHM} = 20.5^\circ$
- $\theta_{95\%} = 47.0^\circ$

Slow axis:

- $\theta_{FWHM} = 8.3^\circ$
- $\theta_{95\%} = 10.0^\circ$

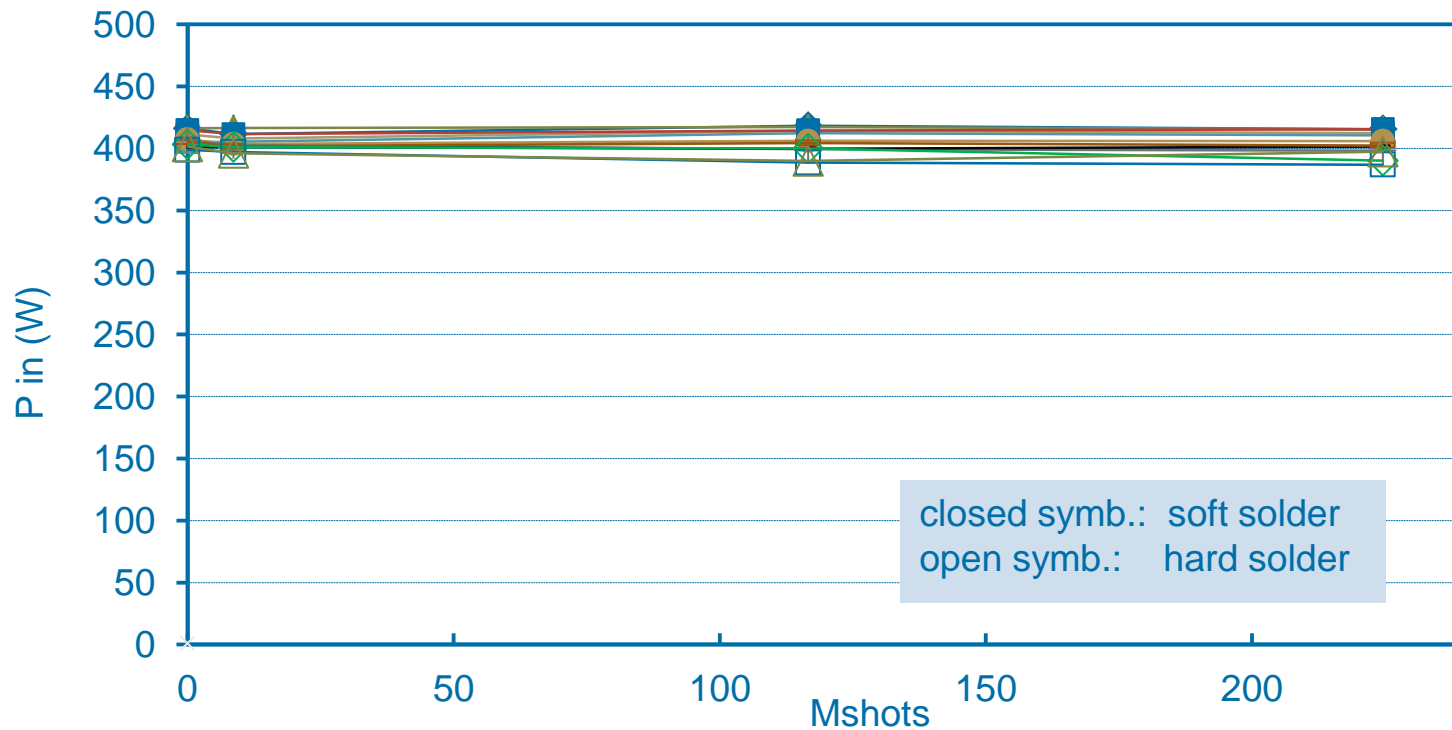
New generation quasi-CW 880 nm Bars

Lifetime test

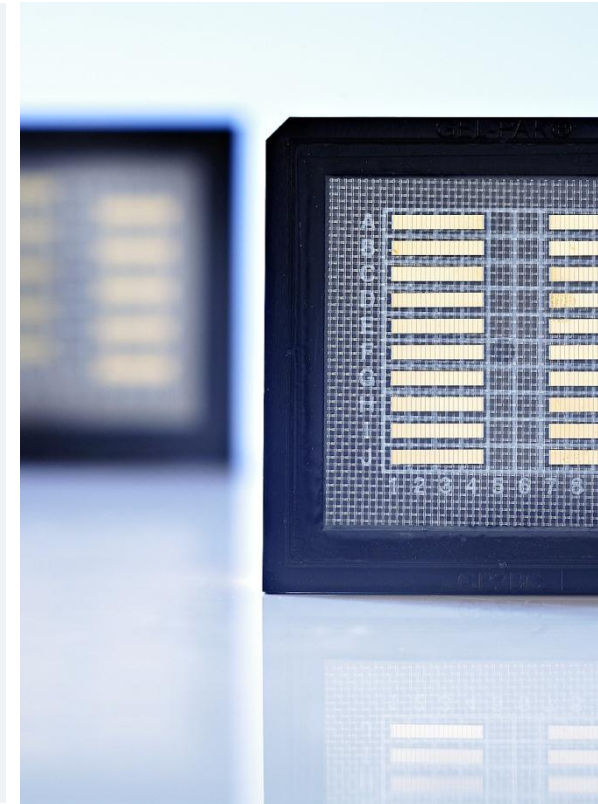
(V)



- device under test: JDL B-75-37-880-TE-500-1.5 on microchannel cooler
- conditions: 400A, 300 μ s, 100Hz (3% d.c.), 25°C
- 224 Mshots as of March, 2014, ongoing



- JENOPTIK and JENOPTIK Diode Lab GmbH
- Semiconductor laser design
- Solution for 940 nm
- Solution for 880 nm
- **Outlook: laser diode stacks**
→ poster tomorrow 15:00 – 16:25



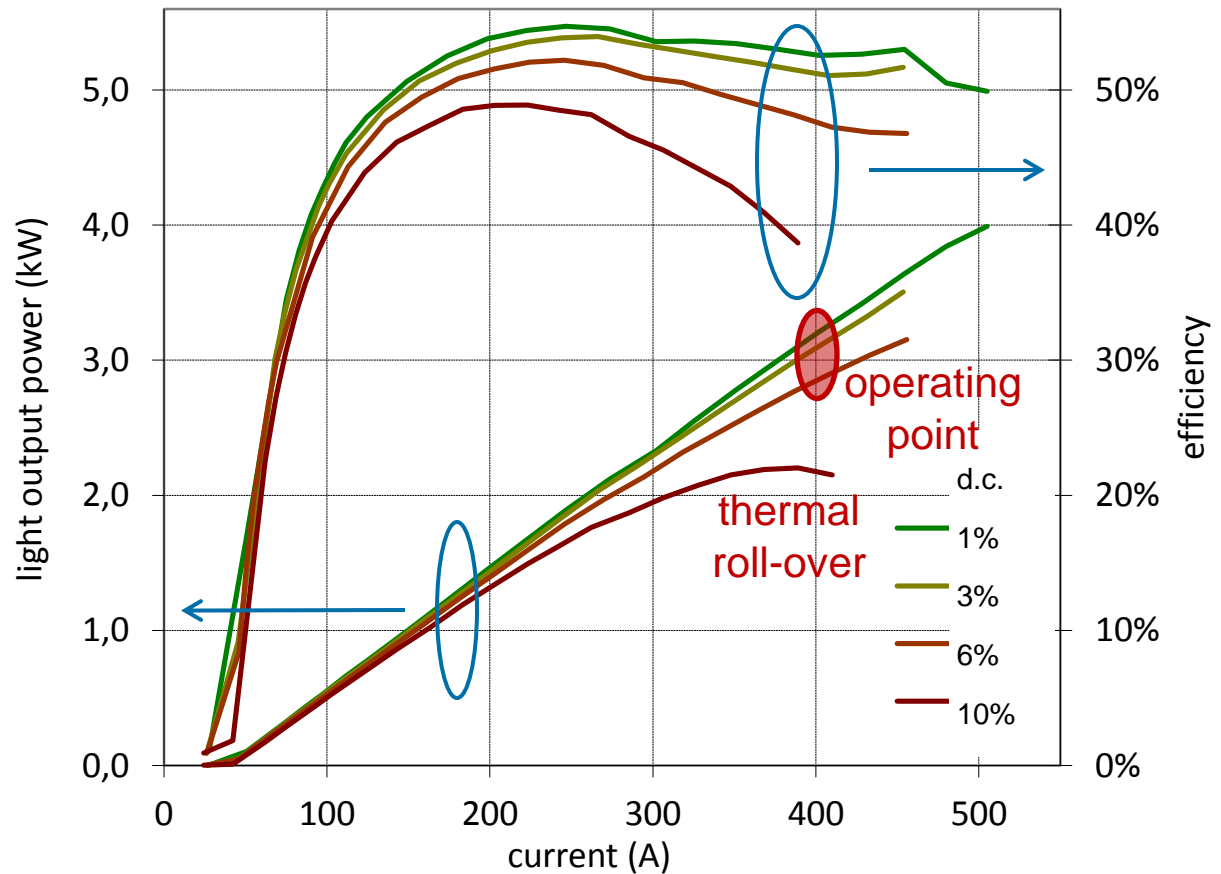
Passively cooled laser diode stacks for pulsed operation



- 880 nm QCW bars
- 8 x in series
- next generation JenLas[®] QCW stack technology

- $t_p = 300\mu s$
- DC
 - 1%
 - 3%
 - 6% ← **limit**
 - 10%

8x JDL-BAB-75-37-880-TE-500-1.5, $t_p=300\mu s$, vary duty cycle



QCW laser diode development:

- **Agnieszka Pietrzak, Ralf Hülsewede, Martin Zorn, Olaf Hirsekorn**
Jenoptik Diode Lab GmbH, Berlin
- *Ferdinand-Braun-Institut, Berlin*

diode laser qualification:

- **Jens Meusel**
Jenoptik Laser GmbH, Jena

diode laser stack assembly:

- **Alex Kindsvater, Matthias Schröder**
Jenoptik Laser GmbH, Jena

- Jenoptik Diode Lab GmbH
development, production and bare bar sale
- new high-power laser bars for QCW operation
 - JDL-BAB-75-37-**940**-TE-500-1.5
 - JDL-BAB-75-37-**880**-TE-500-1.5
- lifetime test started
- Outlook: laser diode stacks
→ poster tomorrow 15:00 – 16:25

